

2° MEETING IU.NET Udine, 10-11 Febbraio 2011

MOdeling and DEsign of Reliable, process variation-aware Nanoelectronic devices, circuits and systems MODERN

ENIAC/CATRENE JTI







- The objective of the **MODERN** project is to develop new paradigms in integrated circuit design which will enable the manufacturing of reliable, low cost, low EMI, high-yield complex products using unreliable and variable devices.
- Specifically, the main goals of the project are:
 - 1. Advanced, yet accurate, models of process variations for nanometer devices, circuits and complex architectures.
 - 2. Effective methods for evaluating the impact of process variations on manufacturability, designreliability and circuit performance.
 - Reliability, noise, EMC/EMI.
 - Timing, power and yield.
 - 3. Design methods and tools to mitigate or tolerate the effects of process variations on those quantities applicable at the device, circuit and architectural levels.

Validation of the modeling and design methods and tools on a variety of silicon demonstrators.







- 1 call ENIAC 2008
- ENIAC projects: industry driven; Research Institutions are to be connected to industrial partners.
- IU.NET connected to european partners; research activity organized with NXP, ST-F and LETI
- "clustering" of Italian partners
- European approval
- IU.NET re-oraginzed activity according to the needs of Italian industries.
- Mis-matching between European DOW and Italian activity





Partner del progetto

| Participant no. * | Participant organisation name | Part. short name | Country | ENIAC member State | EU Member State/Assoc country |
|---------------------|---|------------------------|-----------------|--------------------------|-------------------------------------|
| 1 | STMicroelectronics SA | ST-F | France | Y | T. |
| 2 | Austriamicrosystems AG | AMS | Austria | Y | Y |
| 3 | Centre Suisse d'Electronique et Microtechnologie | CSEM | Switzerland | N | Ý |
| 4 | Elastic Clocks S.L. | ELX | Spain | Y | Ý |
| 5 | TEKLATECH A/S | TEXL | Denmark | Y | X |
| 6 | Infineon Technologies Austria AG | IFXA | Austria | Y | Y |
| 7 not used | en especie analysis and | 1. MAR & 101 | | | |
| 8 | IMEP-LAHC Laboratory | IMEP | France | Y | Y |
| 9 | ST Microelectronics (Crolles 2) SAS | STF2 | France | Y | Y |
| 20 | and the second state of the second state of the | 1.315 | | 100 C | |
| 11 | Consorzio Nazionale Interuniversitario per la Nanselettronica | UNET | Italy | Ŷ | Y |
| 12 | CEALERI | 1.1.71 | France | ¥ | N. |
| 13 | Montpellier Laboratory of Computer Science, Robotics and Micro-electronics | LIRM | France | Y | Y |
| 14 not used | | | | Y | Y |
| 15 | Numonya Italy Srl | NMX | Italy | Y | Y |
| 16 (Coordinator) | NXP Semiconductors Netherlands B.V. | NXP | The Netherlands | Y | Y |
| 17 not used | | | | | |
| 18 | Politecnico di Torino | POLL | Italy | Y | Y |
| 19 | STMicroelectronics S.r.I. | ST-1 | Italy | Y | Y |
| 20 | Synopsys Switzerland LLC | SNPS | Switzerland | N. | Y |
| 21 | Thales SA | THL | France | Y | Y |
| 22 | TIEMPO SAS | TMPO | France | Y | Υ. |
| 23 | Delft University of Technology | TUD | The Netherlands | Y | Y |
| 24 | Eindhoven University of Technology | TUE | The Netherlands | Y | Y |
| 25 | Graz University of Technology | TUGI | Austria | Ý | Y |
| 26 | Vienus University of Technology | TUW | Austria | Ŷ | Y |
| 27 | Alma Mater Studiorum - Università di Bologna | UNBO | Italy | Y | Y |
| 28 | University of Calabria | UNCA | Italy | Y | Y |
| 29 | The University of Glasgow | UNGL | United Kingdom | N | Y. |
| 30 | Sapienza Università di Roma | UNRM | Italy | Y | - Y |
| 31 | Universitat Politecnica de Catalunya | UPC | Spain | Ŷ | Ŷ |













Costs and funding

| | | Costs and funding | | |
|-------------------|-------------|--------------------------------|--------------------------------------|--|
| Participant n" | Country | Total eligible costs (in €) | Maximum ENIAC contribution (in €) | Maximum national contribution (in €) (where applicable) ¹ |
| 1 | France | 731 711 | 122 196 | 97 318 |
| 2 | Austria | 906 594 | 151 401 | 226 649 |
| 3 | Switzerland | 551 250 | 92 059 | 0 |
| 4 | Spain | 238 000 | 39 746 | 126 854 |
| 5 | Denmark | 157 569 | 26 314 | 0 |
| 6 | Austria | 1 478 010 | 246 828 | 369 502 |
| 8 | France | 327 666 | 54720 | 272 946 |
| 9 | France | 1 085 032 | 181 200 | 144 309 |
| 10 | Greece | 665 500 | 111 139 | 221 612 |
| 11 | Italy | 680 000 | 113 560 | 226 440 |
| 12 | France | 1 221 850 | 202.400 | 210 222 |
| 13 | France | 374 053 | 62 467 | 311 586 |
| 15 | Italy | 960 000 | 160 320 | 257 180 |
| 16 | Netherlands | 5 548 950 | 926 675 | 1 015 458 |
| 18 | Italy | 1 360 000 | 227 120 | 452 880 |
| 19 | Italy | 2 512 000 | 419 504 | 623 996 |
| 20 | Switzerland | 432 000 | 72 144 | 0 |
| 21 | France | 1 280 338 | 213 816 | 170 285 |
| 22 | France | 974 220 | 162 695 | 129 571 |
| 23 | Netherlands | 1 255 152 | 209 610 | 417 966 |
| 24 | Netherlands | 252 000 | 42 084 | 83 916 |
| 25 | Austria | 189 000 | 31 563 | 111 510 |
| 26 | Austria | 189 027 | 31 568 | 111 526 |
| 27 | Italy | 680 000 | 113 560 | 226 440 |
| 28 | Italy | 340 000 | 56 780 | 113 220 |
| 29 | UK | 1 488 000 | 64 128 | 0 |
| 30 | Italy | 340 000 | 56 780 | 113 220 |
| 31 | Spain | 208 200 | 34 700 | 173 500 |
| Total | | | 4 247 096 | 6 308 204 |





1343







- **MODERN** is targeting the transversal Sub-Programme SP7: Design Methods and Tools for Nanoelectronics.
- **MODERN** is a plurality of complementary industrially driven projects for Design Methods and Tools for Nanoelectronics; it will address most of the areas recommended in the ENIAC Annual Work Programme 2008, and in particular:
 - Device, circuit, and system variability and reliability (WP2 and WP3)
 - Hardware/software model driven high-level synthesis/flow/reuse/design. (WP3 and WP4)
- Indicative resources: **206** person-years over 3 years



U.NET Motivation and background

• Motivation 1: Process Variations

To fully account for the effects of process variation, it is essential: (1) To model process variations for VLSI systems in an accurate, but still efficient way at different levels of abstractions. (2) To devise efficient methodologies to evaluate the impact of variation on various figures of merit, such as timing, power and yield. (3) To adopt design solutions that are able to keep under control the effects of variations on this quantities.

• Motivation 2: Electro Magnetic Compatibility (EMC)

- by creating circuits that are robust with respect to short-term variations, such as those induced by power supply ripple and noise, one may very well reduce the effects of EMI, which are due to periodic sharp waveforms. In MODERN, new design methodologies, along with architectural solutions based on asynchronous and de-synchronization techniques will be defined and developed, in order to provide product designers with an effective approach to reduce EMI, while satisfying the traditional constraints and mitigating the impact of Process Variability, in order to fabricate more reliable and robust electronic systems.
- Motivation 3: Management of complex systems enabled by new technologies
 - parallel architectures are an opportunity to work around process variation issues. Industries involved in systems development have experience of complex architectures at both system equipments and system-on-chip levels. This type of experience is applied to applications with either real-time or safety critical constraints.





Task T2.2: PV-aware device simulation

Focus in this task is on activities to include variability in device simulation tools. TCAD will be used to assess various device architectures in standard CMOS but also in other technologies concerning variability, to identify major sources for variability on simulation level already; process sensitivities will be investigated. New methods will be developed to generate statistical circuit simulation parameter through TCAD, with smart approaches (other than brute force). Furthermore mixed mode device/circuit simulations will be carried out. ...**UNET** will put emphasis on the device simulation of memory cells, transistors for high- performance logic circuits and for low-power mixed-mode applications: At the beginning a methodology will be defined to evaluate the impact of process tolerances and intrinsic variability on the dispersion of electrical parameters with computationally efficient TCAD. Viable modelling approaches to efficiently incorporate new physics phenomena and their fluctuations in future devices will be worked out, taking into account the impact of variations of the dielectric thickness, channel doping and stress conditions. In addition a methodology will be defined to evaluate the impact of PV on a single cell within a memory array. Mixed-mode device/circuit simulation methodologies will be looked into to analyze the impact of fluctuations on the performance of simple digital and analog circuit blocks.



Task T2.3: Electrical characterization of PV, software (TCAD) / hardware comparison & calibration

Basic effects of PV will be characterized based on hardware in different technologies, ranging from mainstream CMOS 45/32nm to new device architectures suitable for 22nm CMOS. Other technologies like NVM or SiC, GaAn/AlGaN power and RF devices will complement the activities. In addition for "non pure digital logic technologies" the devices studied will span over many technology generations, so the PV-methodologies will cover a wide spectrum of devices. In general major sources for PV will be identified and characterized wrt/ further scaling. Variability effects and their sensitivities will be investigated from planar bulk device concepts to new architectures on SOI in 2D or 3D. Device simulation results will be compared to measurements and will be calibrated on hardware data to verify PV methodology and physical understanding of major sources of PV in above technologies. It has to be emphasized that there is a strong link between some activities in WP2.3 and in WP5.1 (silicon demonstration: "test structures for PV analysis"), since test structures and their electrical characterization can be considered as an important step towards demonstration already.

...**UNET** will concentrate on experimental methodologies for characterization of PV on test structures, single cells or simple arrays and on methodologies for evaluation of cell statistics on array performance, for 45 and 32nm planar CMOS and for Non Volatile Memory technologies.





Task T2.4: Correlation between PV and reliability, reliability modeling

The impact of process variability on existing device reliability degradation models will be clarified. Aging measure- ments will be performed on test structures: Device degradation mechanisms will be identified based on silicon, their effect on PV parameters will be characterized and modeled to allow for a better description of aging during operation.

...**UNET** will work on methodologies to design reliability experiments that allow characterizing the impact of PV on test structures, single cells or simple arrays, on 45nm & 32nm planar CMOS, and on Non-Volatile Memories. It will include the development of compact models including aging effects.

Task T2.5: PV-aware compact modelling

PV and reliability effects have to be implemented in device compact models to be able to accurately describe the impact of variability on circuit operation. Implementation methodologies will be worked out and adopted in standard compact modeling.

...With further scaling it becomes mandatory to come up with viable analytical modeling approaches to efficiently incorporate new physics phenomena and their fluctuations in compact models, including quasi ballistic transport (QTB) features and the impact of variations of the dielectric thickness, channel doping and stress conditions, and with viable compact modeling approaches to reach the best trade-off between accuracy and statistics, including variability. **UNET** will address these aspects involving new physics for 45/32nm CMOS and for non-volatile memory technologies.





| 2: PV-aware device simulation | | 29 |
|---|--------|----|
| inition of a methodology to evaluate the impact of process tolerances intrinsic variability on the dispersion of electrical parameters with a uputationally efficient TCAD methodology. | PI | 5 |
| ble modeling approaches to efficiently incorporate in device | UD | 2 |
| ulators new physics phenomena and their fluctuations in future | BO | 5 |
| ices, including hole and electron mobility, taking into account the | | |
| act of variations of the dielectric thickness, channel doping and | | |
| ss conditions. | | |
| inition of a methodology to evaluate the impact of process variability | POLIMI | 11 |
| he single cell within a memory array (say RTN: random telegraph | | |
| se, RDF: random dopant fluctuations). | | |
| relopment of mixed-mode device/circuit simulation methodologies to | ₩Ð | 4 |
| lyze the impact of fluctuations on the performance of simple digital | | |
| analog circuit blocks. | | |
| ordinamento | | 2 |

| 3: Electrical characterization of PV, software (TCAD) / | | 12 |
|--|--------|----|
| dware comparison & calibration | | |
| inition of a methodology to design characterization experiments that | MORE | 2 |
| w characterizing PV on test structures, single cells or simple arrays. | POLIMI | 3 |
| relopment of Compact Models with emphasis on the trade-off | MORE | 2 |
| veen "physics based" and "statistics": starting from the selection of | FE | 2 |
| ificant parameters, it will define a methodology to reduce the | | |
| iber of parameters. | | |
| inition of a methodology to evaluate cell statistics on array | FE | 2 |
| formance. | | |
| ordinamento | | 1 |





| 4: Correlation between PV and reliability, reliability modeling | 2. | 10 |
|---|--------|----|
| inition of a methodology to design reliability experiments that allow | MORE | 3 |
| racterizing the impact of PV on test structures, single cells or simple | POLIMI | 3 |
| ys. | | |
| elopment of Compact Models including aging effect. | MORE | 3 |
| ordinamento | | 1 |
| 5: PV-aware compact modeling | | 15 |
| ble analytical modeling approaches to efficiently incorporate new | UD | 2 |
| sics phenomena and their fluctuations in compact models, including | | |
| si ballistic transport (QTB) features and the impact of variations of | | |
| dielectric thickness, channel doping and stress conditions. | | |
| ble Compact Modeling approaches to reach the best trade-off | MORE | 1 |
| veen accuracy (nm scaled physics requires a lot of parameters to | FE | 1 |
| cribe physical phenomena) and statistics (few significant parameters | POLIMI | 6 |
| desirable to catch at best the dispersion of electrical characteristics), | PI | 3 |
| uding variability. | | |
| ordinamento | | 2 |





| Task | D | Description | DUE DATE | UniBO | UniFE | UniMORE | UniPI | UniUD | PoliMI |
|--|---------|---|----------|-------|-------|---------|-------|-------|--------|
| | D 2.2.2 | Device simulation analysis of dominant variability sources in 45nm planar bulk CMOS technologies, and Discrete Power Device, SiC, GaN/AlGaN technologies. Prototype implementation of the treatment of individual dopants and traps in the device modeling tools | 12 | 2 | | | 2 | 1,5 | |
| | D 2.2.3 | Device simulation analysis of dominant variability sources in state-of-the-art Non-Volatile-Memory technologies | 18 | | | | | | 3 |
| T2.2: PV- aware device simulation | D 2.2.4 | Forecast of the magnitude of statistical variability in 32nm planar bulk CMOS devices via device simulation. Efficient compact model extraction procedures for modeling process variations and device fluctuations | 24 | 3 | | | 2 | | |
| | D 2.2.5 | Application of mixed-mode device-circuit simulations for the analysis of the impact of fluctuations. TCAD based assessment of PV effects of potential 22nm device architectures. | 27 | 2 | | | | 4 | |
| | D 2.2.6 | Sensitivity analysis of Non Volatile Memory device performance as a function of individual trap position. Toolbox (methodologies, models, tools) to make dominant variability effects accessible to industrial usage of TCAD, outlook to 16nm device architecture robustness using MASTAR | 36 | | | 5 | | | 10 |
| T2.3: Electrical characteriza tion of PV, software | D 2.3.1 | Characterization of the influence of variability sources in planar bulk CMOS devices down to 45nm. Experimental characterization of Non-Volatile- Memory devices in the presence of PV. Parametric mismatch fluctuation effects in 32 nm FinFETs, first PV results on 22nm FDSOI MOSFETS | 12 | | | | | | 2 |
| (TCAD) / hardware comparison & calibration | D 2.3.3 | Identification of most relevant process variations in planar bulk CMOS devices down to 32nm, parameter fluctuation effects based on hardware. Sources for PV in new device architectures, suitable for 22nm CMOS; major deltas in comparison to standard planar bulk CMOS | 30 | 1 | 3 | | 1.5 | | |





| T2.4: Correlation between PV | D 2.4.2 | Hardware results of aging measurements available, on planar bulk CMOS technologies | 24 | | | | | | |
|--|--|--|----|-----------|-----------|------------|--------------|--------------|------------|
| and reliability, reliability modeling | D 2.4.3 | Implementation of statistical degradation effects into aging models, hardware calibration of degradation effects | 33 | | | 3 | | | 2 |
| T2.5: PV- aware | D 2.5.1 | PV-aware circuit-level models for standard CMOS technologies (down to 45nm), and Non-Volatile-Memory technologies, and Discrete Power Device,SiC, GaN/AlGaN technologies. State-of-the-art based statistical models, based on hardware and/or TCAD. | 18 | | 1 | 2 | | | 3 |
| compact modeling | D 2.5.2 | Statistical PV-aware models for planar bulk CMOS generation devices (down to 32nm) | 30 | | 1 | | | | |
| | D 2.5.3 | PV-aware circuit-level models for 45nm analog CMOS technology; Modeling of additional variability sources of 3- dimensional device architectures, for new device architectures for 22nm | 33 | | | | 2 | 2 | |
| | TOTALE MESI UOMO (tra parentesi quelli dichiarati e usati per la suddivisione del budget) | | | 8 (10) | 5 (5) | 10 (10) | 7,5 (7,5) | 7,5 (7,5) | 20 (20) |
| | BUDGET CORRISPONDENTE (€) | | | | 28.333,00 | 56.666,00 | 42.500,00 | 42.500,00 | 113.333,00 |





| | Attività | Effort | Partner Tecnologico | Deliverable | Due Date |
|----------|--|--------|------------------------|-------------|-------------|
| Unità-BO | Implementation of a mobility model accounting for different stress configurations, different crystallographic orientations and ultra-thin body effects in advanced MOSFETs. Sensitivity analysis with respect to uniform variations of doping, stress and oxide/interfacial layer thickness. Application to the analysis of FinFETs. | 2 | NMX | 2.2.2 | 12 |
| | Sensitivity analysis of Non Volatile Memory device performance as a function of individual trap position. Numerical analysis by means of Sentaurus Device including a PMI model for the electron and hole mobility, incorporating mechanical stress, oxide/interfacial layer thickness and high-k stack effects. | 3 | NMX | 2.2.6 | 36 |
| | Application of mixed-mode device-circuit simulations for the analysis of the impact of fluctuations. | 2 | | 2.2.5 | 27 |
| | Analysis of new sources for PV in device architectures suitable for 22nm CMOS; major deltas in comparison to standard planar bulk CMOS. | 1 | | 2.3.3 | 30 |
| | Coordinamento | 2 | | | |
| | TOTALE | 10 | | | |





| | Attività | Effort | Partner | Deliverable | Due |
|----------|---|--------|-------------|-------------------------------|------|
| | | | Tecnologico | | Date |
| | Comprehensive literature overview of statistical modeling and PV aware analysis techniques. | 1 | NMX | D2.5.1 | 18 |
| Unità-FE | Evaluation of Hamer and maximum gain routine capabilities and limitations as parameter extraction methodologies. Data analysis tools for statistical studies on main technological parameter variations (oxide thickness, doping and threshold voltage). Usage of BSIM simulations/models for the analysis of PV variations. Experimental analysis of mobility variations as a function of operating conditions and BSIM modeling capabilities. Experimental characterization of temperature effects on mismatch and variations. | 3 | NMX | D2.3.3 (WP5 D5.1.3 NMX) | 30 |
| | Investigations on compact mobility model capabilities to match temperature dependence of parameter variation. | 1 | NMX | D2.5.2 | 30 |
| | TOTALE | 5 | | | |





| | Attività | Effort | Partner | Deliverable | Due |
|------------|---|--------|-------------|-------------|------|
| | | | Tecnologico | | Date |
| | Modelli di correnti di leakage in dielettrici di | 3 | NMX | D2.2.6 | 36 |
| | tunnel e di interpoly $(SiO_2, Al_2O_3, stack)$ | | | D2.4.3 | |
| RE | compositi eventualmente con altri materiali high- | | | D2.5.1 | |
| Θ | k) per memorie a FG | | | | |
| M | Integrazione in SW commerciale | 1 | NMX, SYN | D2.2.6 | 36 |
| Unità-MORE | Estensione del modello al punto 1 per materiali | 2 | NMX | D2.4.3 | 33 |
| ni | memorie charge-trapping | | | | |
| n | Modellizzazione di rumore RTN su corrente di | 3 | NMX | D2.4.3 | 33 |
| | GATE su stack diversi (SiO ₂ , Al ₂ O ₃ , HfO ₂ , stack | | | | |
| | compositi) | | | | |
| | Compact models of selected aging effects | 1 | NMX | D2.4.3 | 33 |
| | TOTALE | 10 | | | |





| | Attività | Effort | Partner Tecnologico | Deliverable | Due Date |
|----------|----------|--------|------------------------|-------------|-------------|
| Id- | | | | | |
| Unità-PI | | | | | |
| | | | | | |
| | TOTALE | 7,5 | | | |





| | Attività | Effort | Partner | Deliverable | Due |
|----------|--|--------|-------------|-------------|------|
| | | | Tecnologico | | Date |
| | Models for new physical effects in advanced MOSFETs (Strain) | 2 | NXP | 2.2.2 | 12 |
| | Fast and efficient models for new physical effects in advanced MOSFETs (quasi ballistic transport) | 2 | NXP | 2.5.2 | 30 |
| -UD | Mixed mode device-circuit simulation . | 0 | | 2.2.5 | 27 |
| Unità-UD | Modello non-locale di mobilità che tenga conto di droganti/trappole discrete e gate oxide roughness. | 2 | NMX | 2.2.6 | 36 |
| | Studio effetto di quantizzazione e conduzione non-uniforme (narrow-width, rounding area attiva,) su celle con scaling aggressivo tipo FinFlash: | 2 | NMX | 2.2.6 | 36 |
| | TOTALE | 8 | | | |





| | Attività | Effort | Partner | Deliverable | Due |
|--------------|---------------------------------------|--------|-------------|-------------|------|
| Unità-PoliMI | | | Tecnologico | | Date |
| | Caratterizzazione sperimentale PV su | 3 | NMX | D2.3.1 | 12 |
| | memorie Flash | | | | |
| | Benchmarking PV su struttura Flash 3D | 3 | NMX | D2.2.3 | 18 |
| | Implementazione modello compatto di | 4 | NMX | D2.5.1 | 18 |
| | PV nella stringa NAND | | | | |
| | Simulazione di effetti PV in memorie | 10 | NMX | D2.2.6 | 36 |
| | Flash scalate | | | | |
| | TOTALE | 20 | | | |





Important dates:

- 1 march 2009 beginning
- 3 yrs duration

Deliverables: D2.2.2: due at M12 - done D2.2.3: due at M18 - done D2.2.4: due at M24 – to be done D2.4.1: due at M6 - done D2.5.1: due at M18 - done D6.2.3: due at M18 - done





Difficoltà tecniche

problemi legati alla clusterizzazione difficoltà legate alla gestione dei template devices partner industriale (numonyx-micron) cambia idea e ri-organizza pubblicazioni inter-unità e con partner

Difficoltà gestionali

difficoltà legate alla contrattualistica e al finanziamento (asincronia progetto/contratto; difficoltà di rendicontazione) difficoltà di comunicazione interna

Input per progetti futuri

migliore comprensione del ruolo di IU.NET nel progetto chiarire ruolo di coordinatore migliorare comunicazione interna favorire interazione tra le Unità di IU.NET meccanismi di controllo per le Unità

